

SP B monitoring meeting 2024 SP B.5 - Production of B and W dust particles

Production of W and B dust particles by MSGA

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OUTLINE:

- MSGA (Magnetron Sputtering Gas Aggregation) system: short presentation and experimental parameters for:
 - Synthesis of W dust in D₂/Ar/H₂O (90% D₂);
 - Preliminary tests of B-based dust in Ar, Kr, and additional gases (H₂, N₂, O₂).
- Dust synthesis rates and properties of the obtained dust (pointing to Deuterium retention for W dust).

• Future experiments.

Effects of H_2O vapors on W dust production.



Main gases: D₂ (90%) and Ar (10%);

- H_2O leaks added (up to 10% partial pressure).
- Deposition duration: 3h for one sample;
- P_{RF} =130 W.





) Effects of H_2O vapors on W dust characteristics.

Morphology (SEM)





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Increasing the H_2O amount, the particle dimension increases, and these become more "disconnected".

Chemical composition (XPS) results





H₂O lead to strong oxidation of the dust particles during their production.

Conclusions on W dust:

- Deuterium retention increases with H₂O content, even if the dust synthesis rate decreases (similar to air leaks obtained last year);
- H₂O leaks lead to strong oxidation of the W dust;
- Formation of D₂O and HDO is observed.

Production of B based dust particles

Experimental setup and parameters



- **Boron** is known for its low sputtering yield;
- RF (130W, 13.56 MHz) is used for sputtering;
- Ar or Kr are main sputtering gases;
- H_2 (20 %) N_2 (1.5%) O_2 (1.5%) were added to increase the nucleation rate;
- Deposition duration: 3h for one sample.

Morphology (SEM)



Conclusions on B dust by MSGA:

- The synthesis rate of the B dust is much smaller when compared to W;
- H₂ addition **does not** increase the amount of dust (like happened with W);
- B NPs synthesis is influenced by the presence of impurities.

Possible future activities (next years):

- W and B dust synthesis in D₂-dominated discharges in the presence of different other gases.

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